

U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.	Serial No.			
				03848.0001 / 3034.1A		09/578,282		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				Applicants:				
APR 02 2001 U.S. PATENT & TRADEMARK OFFICE				BEECHER et al.				
				Filing Date	TECH CENTER 1600 Group AB REC'D 1624			
				May 25, 2000		1624 REC'D 1624		
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Piling Date Is Appropriate	
JE	AA	5,242,974	09/07/93	Holmes	525	54.11	1600/2900	
JE	AB	5,679,773	10/21/97	Holmes	530	334	1600/2900	
JE	AC	6,083,697	07/04/00	Beecher et al.	435	6	1600/2900	
	AD						1600/2900	
	AE						1600/2900	
	AF						1600/2900	
	AG						1600/2900	
	AH						1600/2900	
	AI						1600/2900	
	AJ						1600/2900	
	AK						1600/2900	
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
JE	AQ	MacDonald et al., "Chemical Amplification in High-Resolution Imaging Systems", Vol. 27, No. 6, June 1994, pps. 151-158.						
JE	AR	Willson, "Introduction to Microlithography", 2 nd Ed., ACS Professional Reference Book, 1994, pps. 212-233.						
	AS							
Examiner	<i>Tom E</i>	Date Considered	<i>10/25/02</i>					
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.</p>								